

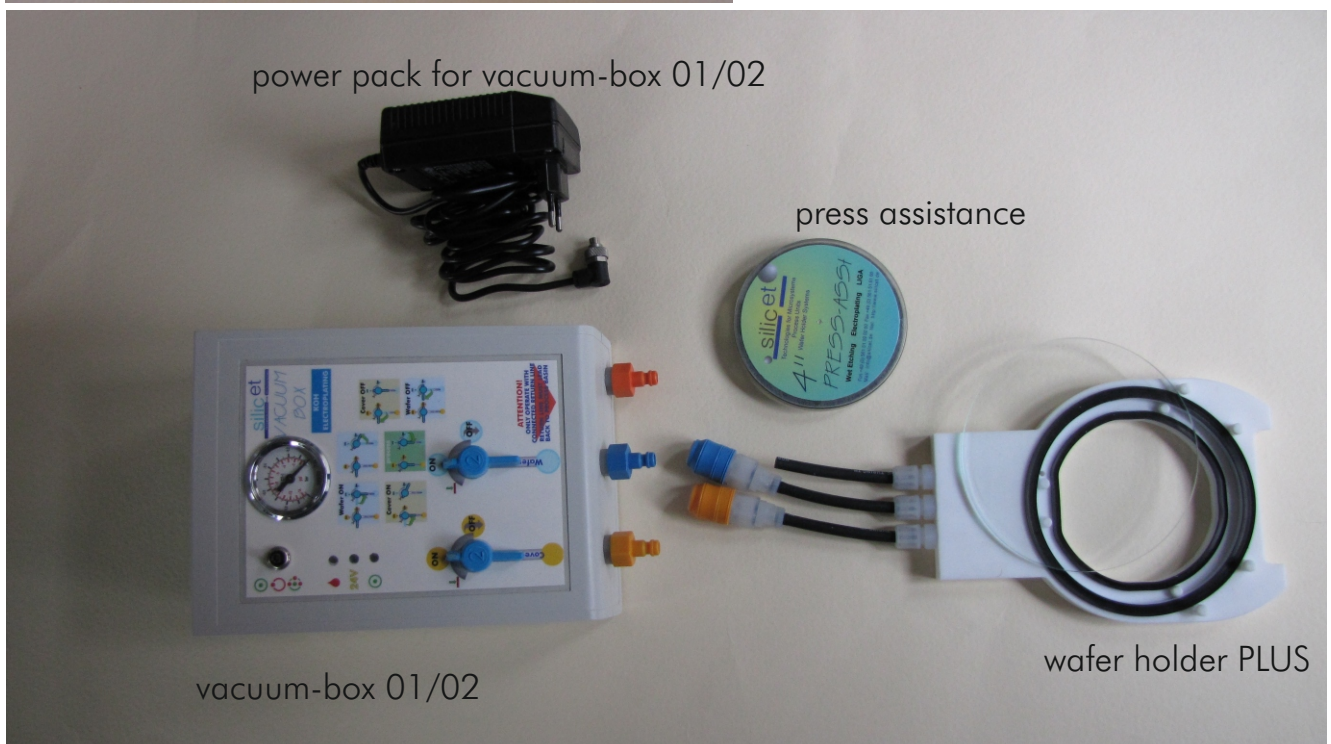
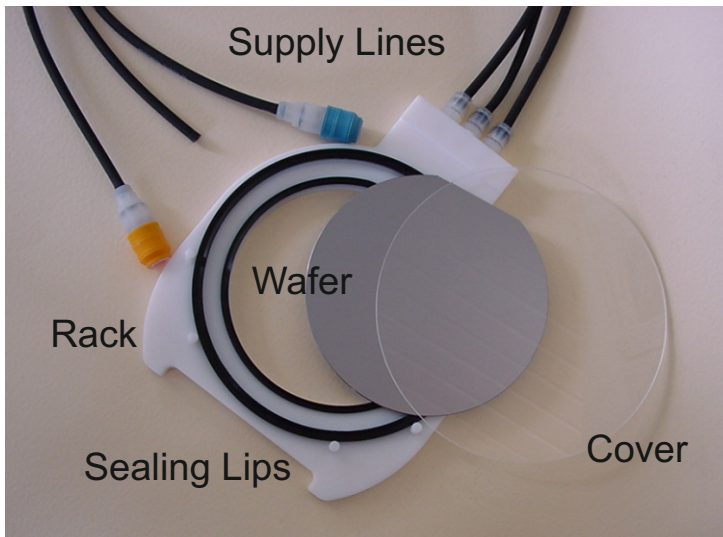
patented
VACUUM-HOLDER PLUS

Our patented Wafer Holder PLUS with easy exchangeable sealing lips, is a new generation of holding device. Created for chemical etching of silicon wafers.

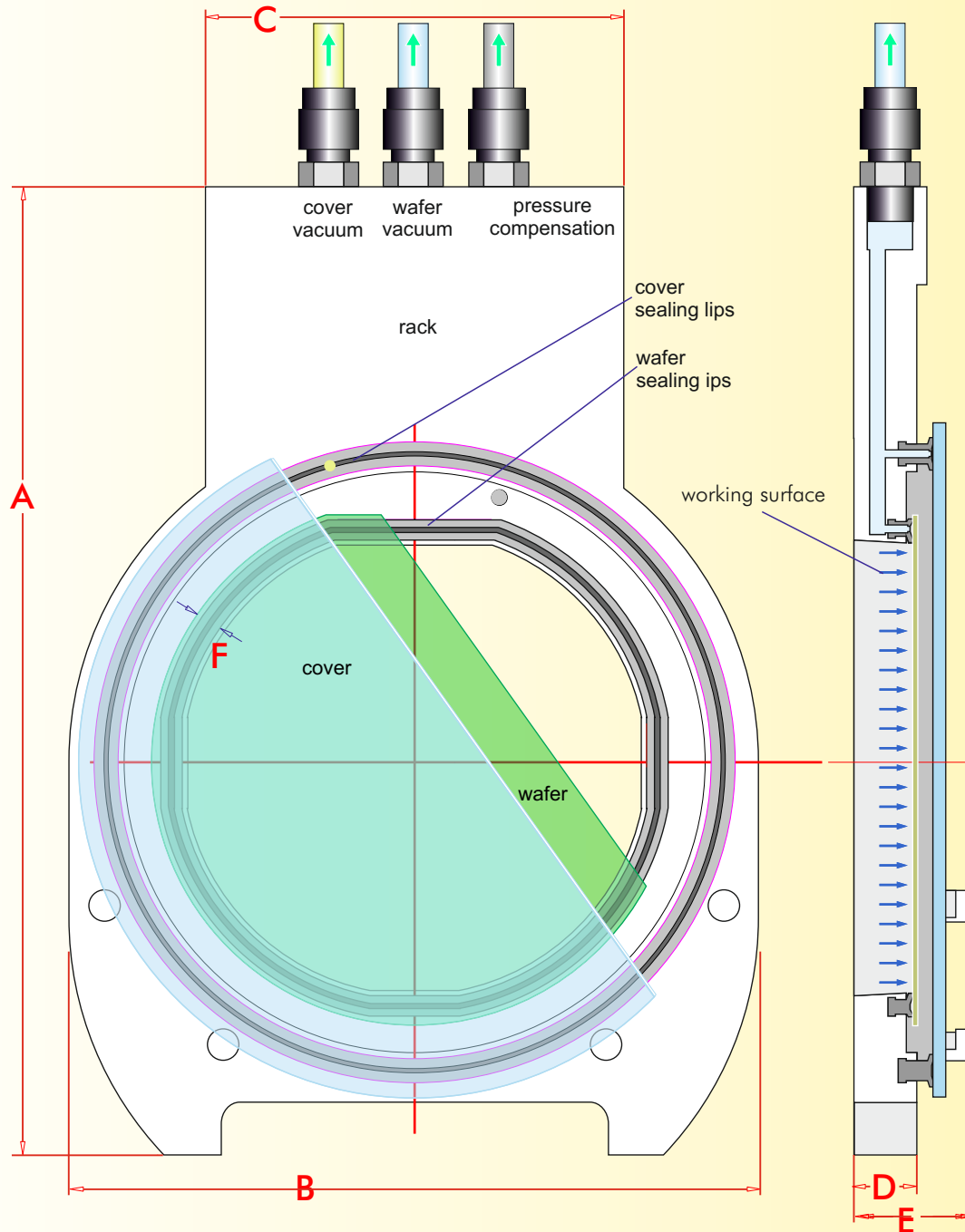
The wafer are held securely by means of a vacuum, thus also protecting them reliably from the etching agent. The Wafer Holder PLUS is equipped with an additional seal, which protects the entire wafer front including the edge from the etching agent.

The protected area behind the wafer is ventilated to provide pressure compensation.

Equipment: Sealing Lips: EPDM/FPM peroxide cured and sulfure-free
Supply line: 3 Norprene or Viton-connecting tubes
Rack: PTFE



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Dimension	Wafer	2"	3"	4"	5"	6"	8"
A - length		122 mm	145 mm	186 mm	239 mm	239 mm	313 mm
B - total width		80 mm	105 mm	132 mm	190 mm	190 mm	263 mm
C - width neck		80 mm	80 mm	80 mm	80 mm	84 mm	100 mm
D - thickness		12 mm	14 mm	14 mm	14 mm	15 mm	15 mm
E - compl. thickness		21 mm	22 mm	22 mm	22 mm	22 mm	24 mm
F - edge exclusion		5 mm	5 mm	5 mm	5 mm	5,5 mm	5,5 mm